

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Gary M. Moore
Assignee: Moore Epitaxial Inc.
Title: METHOD OF CONTROLLING GAS FLOW TO A SEMICONDUCTOR
PROCESSING REACTOR
Serial No.: Unknown Filed: Herewith
Examiner: Unknown Group Art Unit: Unknown
Docket No.: MTEC101001

Monterey, CA
January 18, 2001

Assistant Commissioner for Patents
Box PATENT APPLICATION
Washington, D.C. 20231

PRELIMINARY AMENDMENT

Dear Sir:

Prior to examination of the above-identified application,
please amend the application as follows.

IN THE TITLE

Please change the title to --Method of Controlling Gas
Flow to a Semiconductor Processing Reactor--.

IN THE SPECIFICATION

Before the first line insert --This application is a
divisional of U.S. Patent Application Serial No. 09/399,611,
entitled "GAS FLOW CONTROLLER SYSTEM", filed on September 20,
1999.

IN THE CLAIMS

Please cancel Claims 1-11, 22-28 without prejudice.

Please add new Claims 35-38 as follows:

--35. A method comprising:

opening a first gas manifold inlet valve coupled between a first regulator and a gas manifold;

regulating a flow rate of a flow of a first process gas through said first gas manifold inlet valve to said gas manifold with said first regulator;

opening a second gas manifold inlet valve coupled between a second regulator and said gas manifold;

regulating a flow rate of a flow of a second process gas through said second gas manifold inlet valve to said gas manifold with said second regulator;

opening a gas manifold exhaust valve coupled between a third regulator and an exhaust; and

regulating a flow rate of a flow of a third process gas through said gas manifold exhaust valve to said exhaust with said third regulator during said regulating a flow rate of a flow of a first process gas and said regulating a flow rate of a flow of a second process gas.

36. A method comprising:

opening a first gas manifold inlet valve coupled between a first regulator and a gas manifold;

regulating a flow rate of a flow of a first process gas through said first gas manifold inlet valve to said gas manifold with said first regulator;

opening a second gas manifold inlet valve coupled between a second regulator and said gas manifold;

regulating a flow rate of a flow of a second process gas through said second gas manifold inlet valve to said gas manifold with said second regulator;

opening a gas manifold exhaust valve coupled between a third regulator and an exhaust;

regulating a flow rate of a flow of a third process gas through said gas manifold exhaust valve to said exhaust with said third regulator during said regulating a flow rate of a flow of a first process gas and said regulating a flow rate of a flow of a second process gas;

closing said first gas manifold inlet valve and said second gas manifold inlet valve to stop said flow of said first process gas and said flow of said second process gas to said gas manifold; and

redirecting said flow of said third process gas from said exhaust to said gas manifold.

37. The method of Claim 36 wherein said redirecting comprises;

closing said gas manifold exhaust valve; and
opening a third gas manifold inlet valve coupled between said third regulator and said gas manifold.

38. A method comprising:

opening a first gas manifold inlet valve coupled between a first regulator and a gas manifold;

regulating a flow rate of a flow of a first process gas through said first gas manifold inlet valve to said gas manifold with said first regulator;

opening a gas manifold exhaust valve coupled between a second regulator and an exhaust;

regulating a flow rate of a flow of a second process gas through said gas manifold exhaust valve to said exhaust with said second regulator, said regulating a flow rate of a flow of a second process gas occurring during said regulating a flow rate of a flow of a first process gas;

closing said first gas manifold inlet valve to stop said flow of said first process gas to said gas manifold; and

redirecting said flow of said second process gas from said exhaust to said gas manifold comprising:

closing said gas manifold exhaust valve; and

opening a second gas manifold inlet valve coupled between said second regulator and said gas manifold.--

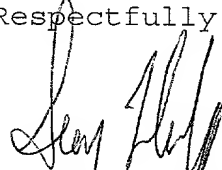
REMARKS

This application is a divisional of U.S. Patent Application Serial No. 09/399,611, filed on September 20, 1999.

Claims 12-21, 29-38 are pending in this application. If the Examiner has any questions relating to the above, the Examiner is respectfully requested to telephone the undersigned Attorney for Applicant.

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Respectfully submitted,



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